Claims

1. A distribution system (10) for a process fluid for chemical and/or electrolytic surface treatment for a substrate, comprising:
   - a first distribution body (11),
   - a substitute body,
   - a framework (14), and
   - sealing units,

   wherein the first distribution body (11) is configured to direct a flow of the process fluid and/or an electrical current to the substrate,
   wherein the first distribution body (11) and the substitute body are arranged to insert the substrate between them,
   wherein the framework (14) is configured to mount the first distribution body (11) and the substitute body relative to each other,
   wherein the framework (14) is further configured to form, together with the first distribution body (11) and the substitute body, a casing surrounding the substrate, and
   wherein the casing is insertable into the distribution system (10) as an independent unit, and
   wherein the sealing units are configured to seal an interface between the framework (14) and the first distribution body (11) as well as an interface between the framework (14) and the substitute body in an electrically insulated manner relative to the surrounding.

2. Distribution system (10) according to claim 1, further comprising a tank (15) configured to receive the casing and suitable to receive an anode.

3. Distribution system (10) according to claim 1, further comprising two chambers, each mounted to one side face of the casing, wherein each chamber is suitable to receive an anode.

4. Distribution system (10) according to one of the preceding claims, wherein the substitute body is a second distribution body (12) also configured to direct a flow of the process fluid and/or an electrical current to the substrate.

5. Distribution system (10) according to one of the preceding claims, wherein the framework (14) comprises a distribution frame element (13) comprising at least a process fluid inlet (2) and/or a process fluid outlet (3).